



Docket No.: 6601P035

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

JAE HEON PARK, ET AL.

Application No.: 09/624,712

Filed: July 25, 2000

For: **METHOD FOR AN IMPROVED DEVELOPING
PROCESS IN WAFER PHOTOLITHOGRAPHY**

Art Group: 1756

Examiner: K. Duda

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PETITION FOR EXTENSION OF TIME PURSUANT TO 37 C.F.R. § 1.136(a)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F. R. § 1.136(a), Applicants for the above-identified application respectfully Petition the Commissioner for a one (1) month extension of time, extending the period for response to November 01, 2003, from the Office Action dated July 01, 2003. The petition filing fee of \$110.00 and a Response to Office Action are attached.

If it should be determined that a longer extension of time is required to prevent this application from being abandoned, please charge any additional fees to Deposit Account No. 02-2666. A copy of the Fee Transmittal is enclosed for deposit account charging purposes.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Date:

10/28/03

Tom Van Zandt, Reg. No. 43,219

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CERTIFICATE OF MAILING/TRANSMISSION

I hereby certify that this correspondence is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Christine Donahue

10/28/03
Date

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